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PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Wen-Ben CHOU et al.

Application No: 09/998,858

Filed: October 31, 2001

For: METHOD AND APPARATUS FOR NITRIDE
 IN SITU SPACER ETCH PROCESS
 IMPLEMENTING INTERFEROMETRY
 ENDPOINT DETECTION AND NON-
 INTERFEROMETRY ENDPOINT MONITORING



Attorney Docket No: LAM2P295

Examiner: Chen, Kin Chan

Group Art Unit: 1765

Date: July 29, 2005

☐ Duplicate for fee processing

Mail Stop: AF
 Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class in an envelope
 Mail to: Commissioner for Patents, Alexandria, VA 22313-1450 on July 29, 2005.

Signed:

Fariba Yadegar-Bandari

Sir:

Transmitted herewith is an Amendment in the above-identified Application.
 The fee has been calculated as shown below.

	Claims Remaining After Amendment	Highest Previously Paid For	Present Extra	SMALL ENTITY RATE FEE	OR	LARGE ENTITY RATE FEE
TOTAL CLAIMS	18	25	00	X 25 = \$ 0.00	OR	X 50 = \$ 0.00
INDEP CLAIMS	03	08	00	X100 = \$ 0.00	OR	X200 = \$ 0.00
[] Multiple Dependent Claim Present and Fee Not Previously Paid				\$180		\$360

TOTAL \$ 0.00

\$ 0.00

- ☐ Applicant(s) hereby petition for a ____ month(s) extension of time to respond to the outstanding Office Action.
- ☒ Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 50-0805.
- ☐ Enclosed is our Check No. _____ in the amount of \$ _____ to cover the additional claim fee and/or extension of time fees.
- ☒ If the required fees are missing or any additional fees are required to facilitate filing the enclosed response, please charge such fees or credit any overpayment to Deposit Account No. 50-0805 (Order No. LAM2P295). A copy of this sheet is enclosed.

Respectfully submitted,
 MARTINE PENILLA & GENCARELLA, LLP

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Response Under 37 C.F.R. § 1.116
Expedited Procedure
Examining Group 1765
PATENT



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Signed: _____

Fariba Yadegar-Bandari

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

This Amendment is filed in response to the Final Office Action mailed on June 1, 2005. Please enter the following amendments and remarks in the above-identified patent application:

Amendments to the claims are reflected in the Listing of Claims begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.